

ATTY DOCKET NO.
00862.022336.1APPLICATION NO.
10/644,032U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICELIST OF REFERENCES CITED BY APPLICANT(S)
(Use several sheets if necessary)APPLICANTS
KAZUTAKA YANAGITA ET AL.FILING DATE
August 20, 2003GROUP
3752

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
Y	5,458,755	10/17/95	Fujiyama et al.	204	224 R	
	5,371,037	12/6/94	Yonehara	437	86	
	5,856,229	1/5/99	Sakuguchi et al.	483	406	
	5,811,348	9/22/98	Matsushita et al.	438	455	
	6,107,213	8/22/00	Tayanaka	438	762	
	5,863,830	1/26/99	Bruel et al.	438	478	
	5,360,748	11/1/94	Nadahara et al.	437	11	
	6,186,193B1	2/13/01	Phallen et al.	141	83	
Y	6,391,743B1	5/21/02	Iwane et al.	438	458	

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT
Y	WO 98/52216	11/19/98	PCT			
Y	EP 0 867 917	9/30/98	Europe			
Y	7-302889	11/14/95	Japan			Abstract
Y	11-45840	2/16/99	Japan			Abstract
Y	5-21338	1/29/93	Japan			Abstract

OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)

Y	R.P. Holmstrom et al., "Complete dielectric isolation by highly selective and self-stopping formation of oxidized porous silicon", <i>Appl. Phys. Lett</i> 42(4), pp. 386-388, 15 February 1983.
Y	A. Uhliir, Jr., "Electrolytic Shaping of Germanium and Silicon", <i>The Bell System Technical Journal</i> , Volume XXXV 1956, pp. 333-347.
Y	K. Nagano et al., "Oxidized Porous Silicon and It's Application", <i>IEICE</i> , vol. 79, pp. 49-54, <i>SSD79-9549</i> , 1979.
Y	T. Unagami, "Formation Mechanism of Porous Silicon Layer by Anodization in HF Solution", <i>Journal of the Electrochemical Society</i> , Vol. 127, No. 2, pp. 476-483, February 1980

EXAMINER

DATE CONSIDERED

5/23/05

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	6,427,747	08/06/02	Omi et al.	156	584	
	6,418,999	07/16/02	Yanagita et al.	156	584	
	6,436,226	08/20/02	Omi et al.	156	344	
	6,427,748	08/06/02	Yanagita et al.	156	584	
	6,350,703	02/26/02	Sakaguchi et al.	438	766	
	6,382,292	05/07/02	Ohmi et al.	156	584	
	6,468,923	10/22/02	Yonehara et al.	438	761	
	6,448,155	09/10/02	Iwasaki et al.	438	464	
	6,313,014	11/06/01	Sakaguchi et al.	438	475	
	20010038153	11/08/01	Sakaguchi et al.	—	—	
	20020045237	04/18/02	Yanagita et al.	—	—	

FOREIGN PATENT DOCUMENTS

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5/23/08

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FORM PTO 1449 (modified)			ATTY DOCKET NO. 00862.022336.1		APPLICATION NO. 10/644,032		
U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE			APPLICANTS KAZUTAKA YANAGITA ET AL.				
LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary)			FILING DATE August 20, 2003		GROUP 1723		
U.S. PATENT DOCUMENTS							
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<i>1</i>		6,427,747 B1	08/06/02	Omi et al.	156	584	
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT
<i>C2</i>		11-005064	01/12/99	Japan			Abstract
OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)							
<i>or</i>		Office Action dated November 24, 2003 of corresponding Korean Patent Application No. 10-2001-0050925.					
EXAMINER	<i>✓</i>		DATE CONSIDERED		<i>5/23/04</i>		

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